

Erratum

Erratum to “A Large-Stroke 3DOF Stage With Integrated Feedback in MEMS”

Bram Krijnen, Koen R. Swinkels, Dannis M. Brouwer,
Leon Abelmann, and Just L. Herder

In the above paper [1], references [32]–[38] were inadvertently removed and are as follows.

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B. Krijnen and K. R. Swinkels are with Demcon Advanced Mechatronics, Enschede 7521PH, The Netherlands (e-mail: bram.krijnen@demcon.nl; koen.swinkels@demcon.nl).

D. M. Brouwer and J. L. Herder are with the University of Twente, Enschede 7522NB, The Netherlands (e-mail: d.m.brouwer@utwente.nl; j.l.herder@utwente.nl).

L. Abelmann is with the Korea Institute of Science and Technology Europe, Saarbrücken 66123, Germany, and also with the University of Twente, Enschede 7522NB, The Netherlands (e-mail: l.abelmann@utwente.nl).

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